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FACSIMILE COVER SHEET

DATE: August 27, 2003
FILE NO: AMAT/2601.P11(4969)/CMP/ECP/RKK
TO: Examiner Sylvia MacArthur
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COMPANY: USPTO
FROM: Keith M. Tackett
PAGE(S) with cover: 11
ORIGINAL TO FOLLOW? ☐ YES ☒ NO

TITLE: Integrated Semiconductor Substrate Bevel Cleaning Apparatus And Method
U.S. SERIAL NO.: 09/785,815
FILING DATE: February 16, 2001
INVENTOR: Mok, et al.
EXAMINER: Sylvia MacArthur
GROUP ART UNIT: 1763
CONFIRMATION NO.: 4127

CONFIDENTIALITY NOTE

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